

Accepted Manuscript

A High Resolution Tilt Measurement System Based on Multi-accelerometers

Yinsheng Weng, Shudong Wang, Hongcai Zhang, Hairong Gu, Xueyong Wei

PII: S0263-2241(17)30345-7

DOI: <http://dx.doi.org/10.1016/j.measurement.2017.05.058>

Reference: MEASUR 4784

To appear in: *Measurement*

Received Date: 30 August 2016

Revised Date: 16 February 2017

Accepted Date: 22 May 2017



Please cite this article as: Y. Weng, S. Wang, H. Zhang, H. Gu, X. Wei, A High Resolution Tilt Measurement System Based on Multi-accelerometers, *Measurement* (2017), doi: <http://dx.doi.org/10.1016/j.measurement.2017.05.058>

This is a PDF file of an unedited manuscript that has been accepted for publication. As a service to our customers we are providing this early version of the manuscript. The manuscript will undergo copyediting, typesetting, and review of the resulting proof before it is published in its final form. Please note that during the production process errors may be discovered which could affect the content, and all legal disclaimers that apply to the journal pertain.

A High Resolution Tilt Measurement System Based on Multi-accelerometers

Yinsheng Weng^{1,†}, Shudong Wang^{1,†}, Hongcai Zhang^{1,†}, Hairong Gu² and Xueyong Wei^{1,*}

¹ State Key Laboratory for Manufacturing Systems Engineering, Xi'an Jiaotong University, 28 West Xianning Road, Xi'an 710049, China; E-Mail: seanwei@mail.xjtu.edu.cn

² National Engineering Laboratory for Highway Maintenance Equipment, Chang'an University, Xi'an 710064, China; E-Mail: guhairong@chd.edu.cn

† These authors contributed equally to this work.

* Author to whom correspondence should be addressed; E-Mail: seanwei@mail.xjtu.edu.cn
Tel.: +86-29-83395381

Abstract: In this paper, a wireless tilt measurement system of high resolution is proposed and demonstrated using multiple MEMS (Micro-electromechanical Systems) accelerometers. The measurement system is mainly composed of MEMS accelerometers as sensing unit, a MCU (Micro Controller Unit), wireless transceivers, battery and a PC terminal. Three MEMS accelerometers are purposely located with specific orientations and the system output is determined from the accelerometer that is most sensitive in the tilting range of the object under testing. The raw measured signal collected by the MCU is processed using Kalman Filter (KF) and the analyzed data is transmitted to the PC terminal by a wireless module. The effect of different KF parameters are analyzed using the Allan variance. After eliminating the accelerometers' installation errors, the measuring resolution of system is found to be 0.02° in the whole range from 0° to 360° . In the step test of tilting back and forth, it is found that the absolute measurement error is less than 0.004° for the step change of 0.05° .

Keywords: Accelerometer; Allan variance; Kalman filter; Tilt measurement

1. Introduction

Tilt is one of the important attitude parameters and its measurement is widely applied in a number of applications such as engineering machinery alignment, human body motion detection, game controllers like Sony's PlayStation, ground motion and land subsidence detection[1–4]. Hence, various tilt sensor and system have been developed accordingly. The main concept behind the tilt sensor is based on the measurement of physical response of a mass moving relative to the fixed casing due to the induced inertial force caused by gravity. The types of moving mass can be solid, liquid or gas and the response of the mass pendulum with respect to gravity can be sensed in various ways including capacitive, resistive, fiber optic, magnetic and thermal [5–12]. It is worthy of noticing from these reported research that the MEMS technology has revolutionized the sensors to enable them with a smaller size and lower

Download English Version:

<https://daneshyari.com/en/article/5006502>

Download Persian Version:

<https://daneshyari.com/article/5006502>

[Daneshyari.com](https://daneshyari.com)